

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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| Applicant(s): | Renken et al. | | |
| Title: | Process Condition Sensing Wafer and Data Analysis System | | |
| Application No.: | 10/685,550 | Filing Date: | October 14, 2003 |
| Examiner: | Samir M. Shah | Group Art Unit: | 2856 |
| Docket No.: | SENS.005US1 | Conf. No.: | 4924 |

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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO OFFICE ACTION AND AMENDMENT

Sir:

This is in response to the final Office Action dated March 29, 2007.

Claim Amendments are reflected in the listing of claims, which begins on page 2 of this paper.

Remarks begin on page 8 of this paper.

Reconsideration is kindly requested in light of the following amendments and remarks.